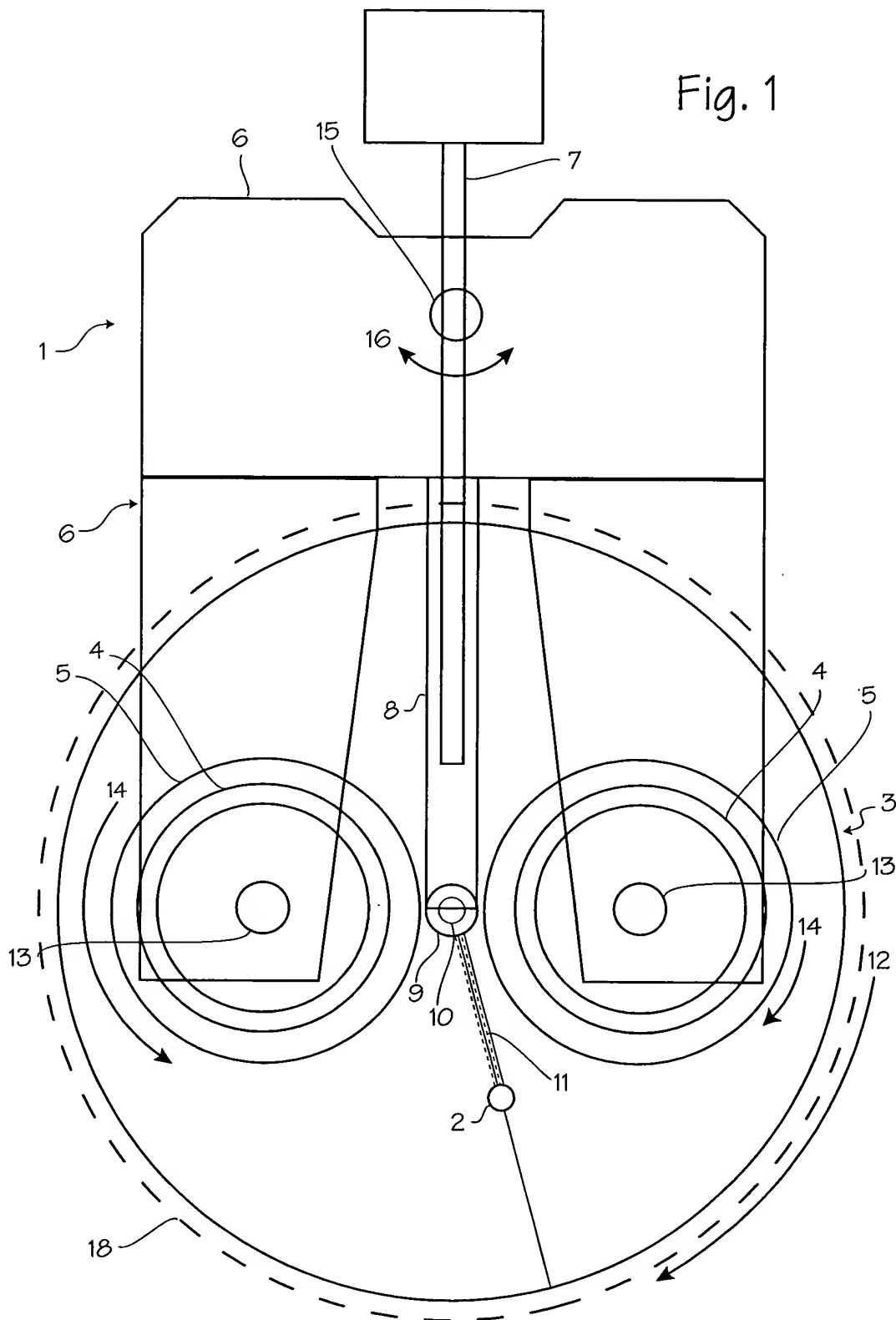


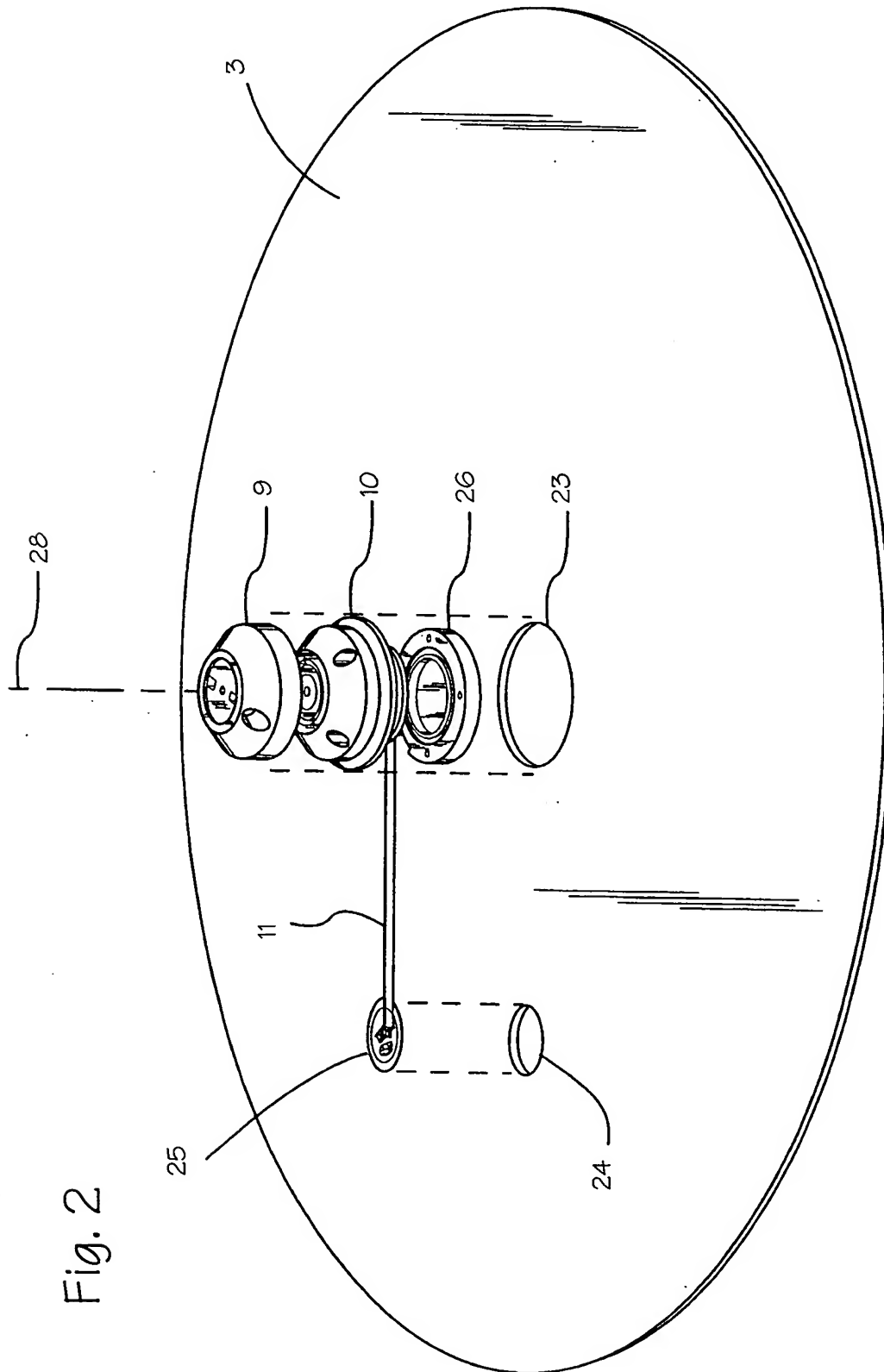
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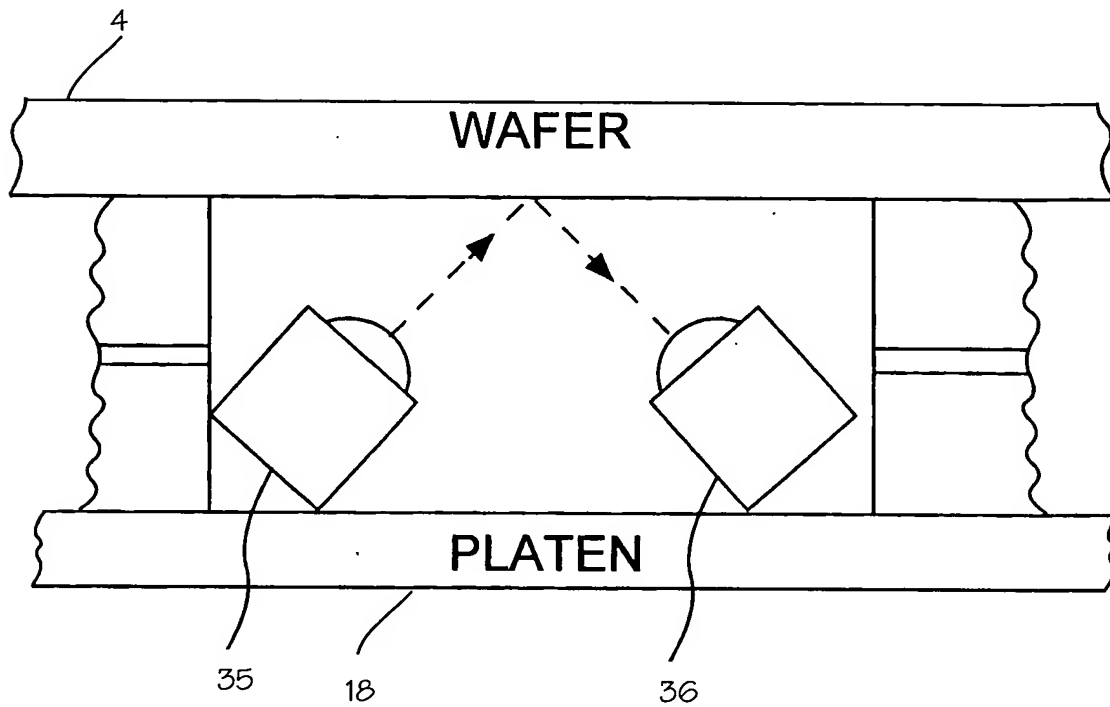


Fig. 4

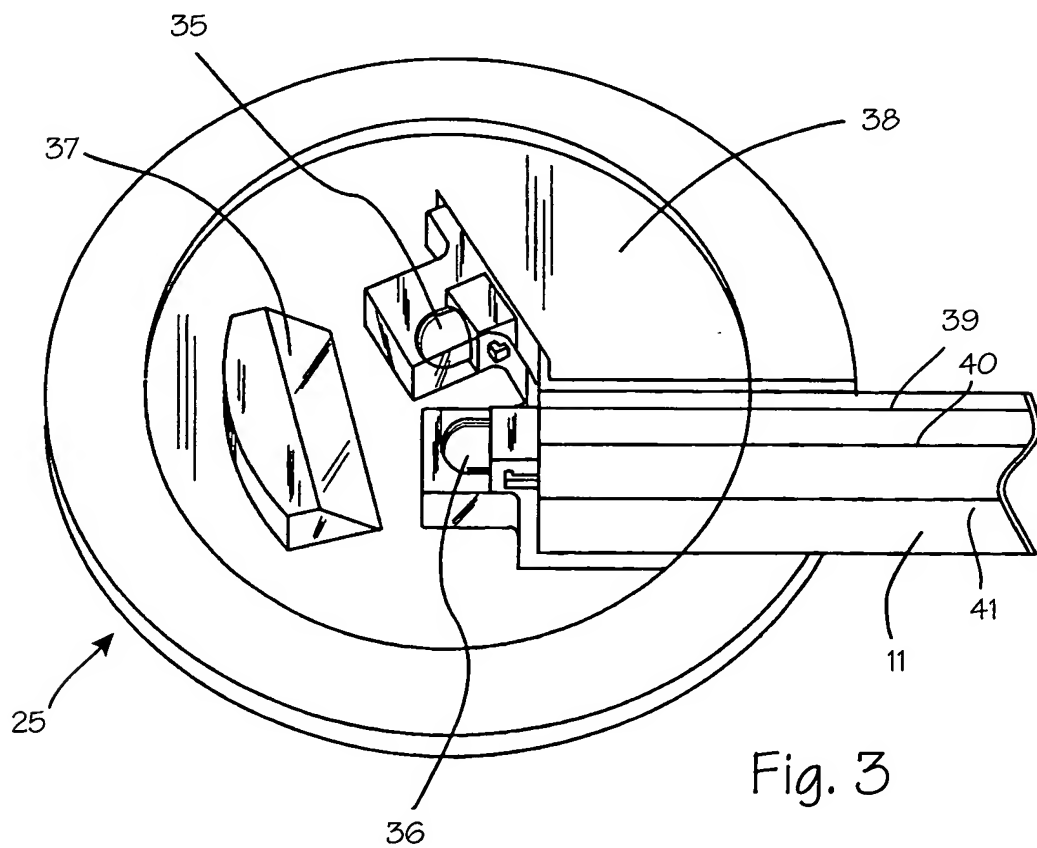
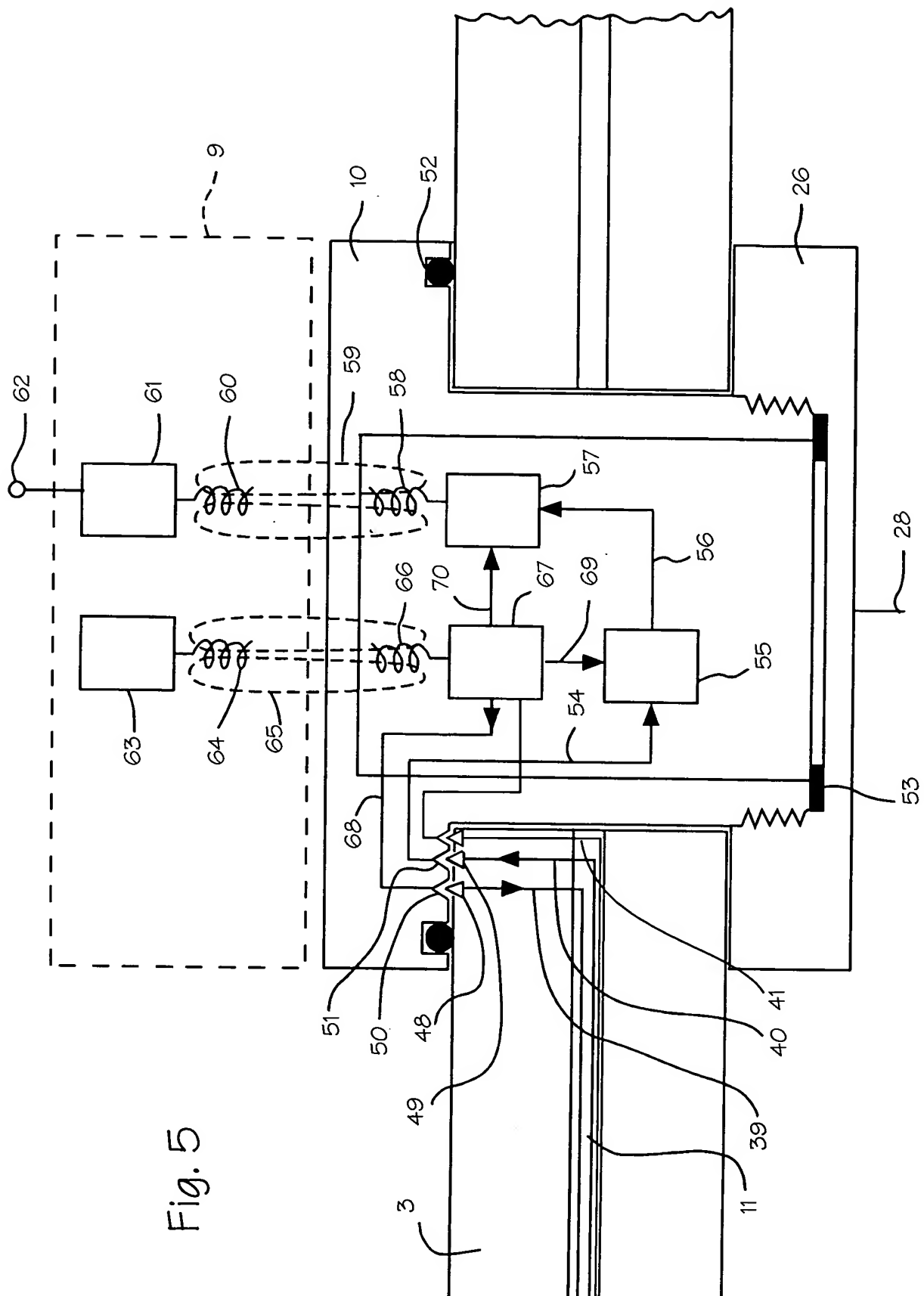


Fig. 3



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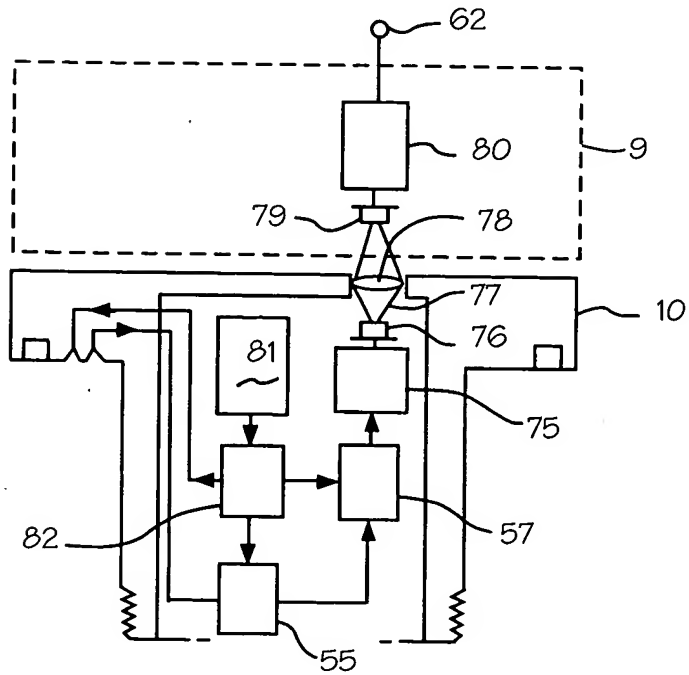


Fig. 6

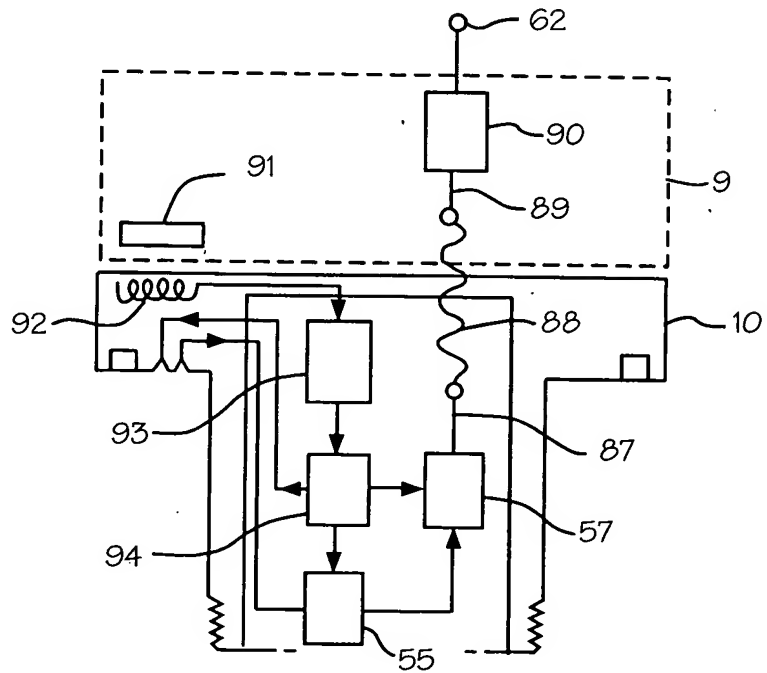


Fig. 7

Fig. 8

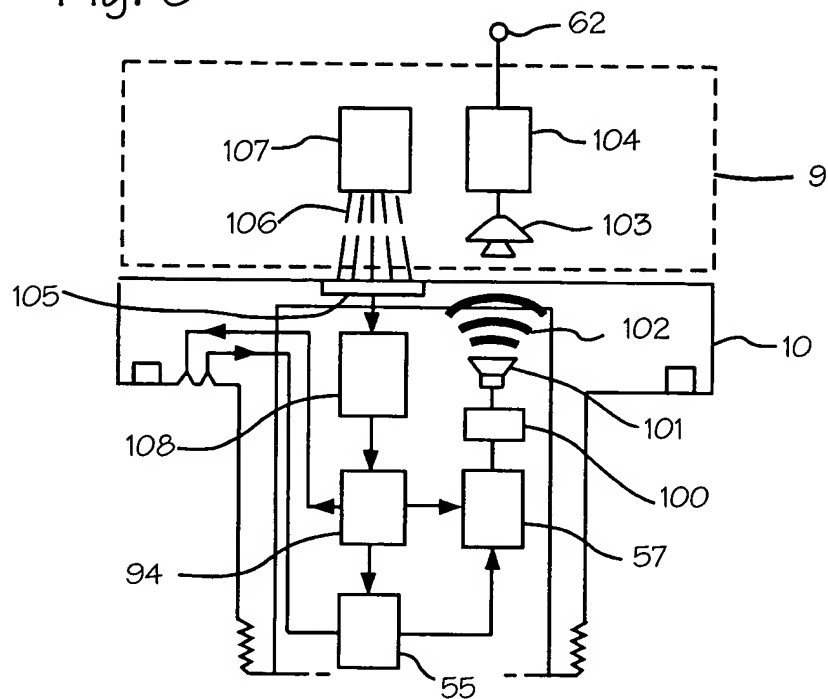


Fig. 9

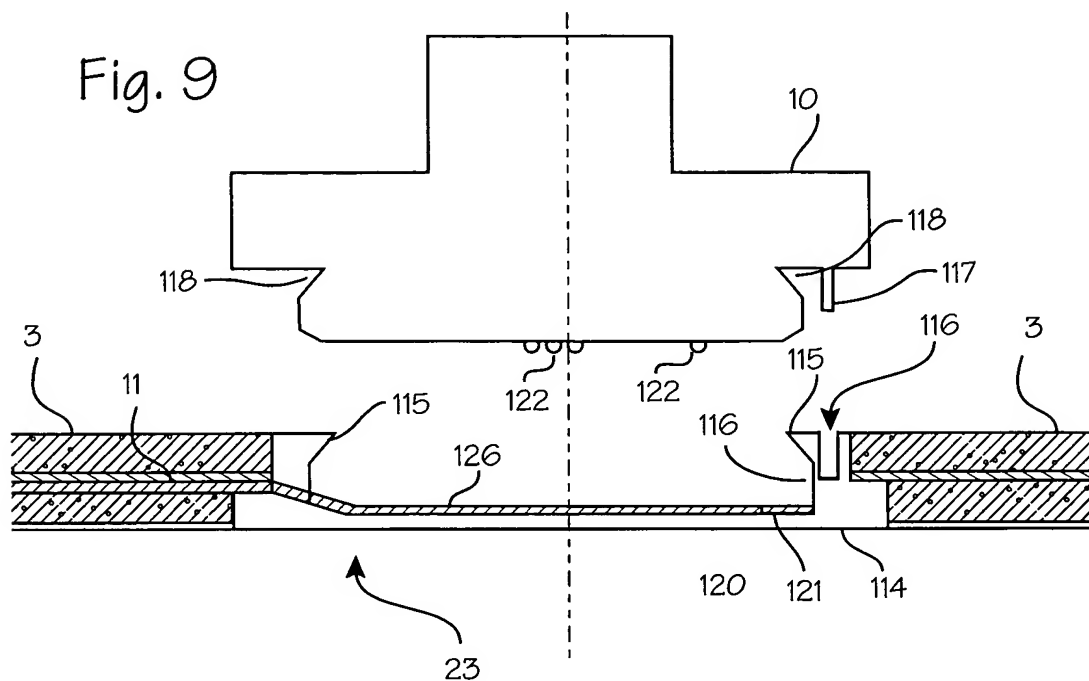
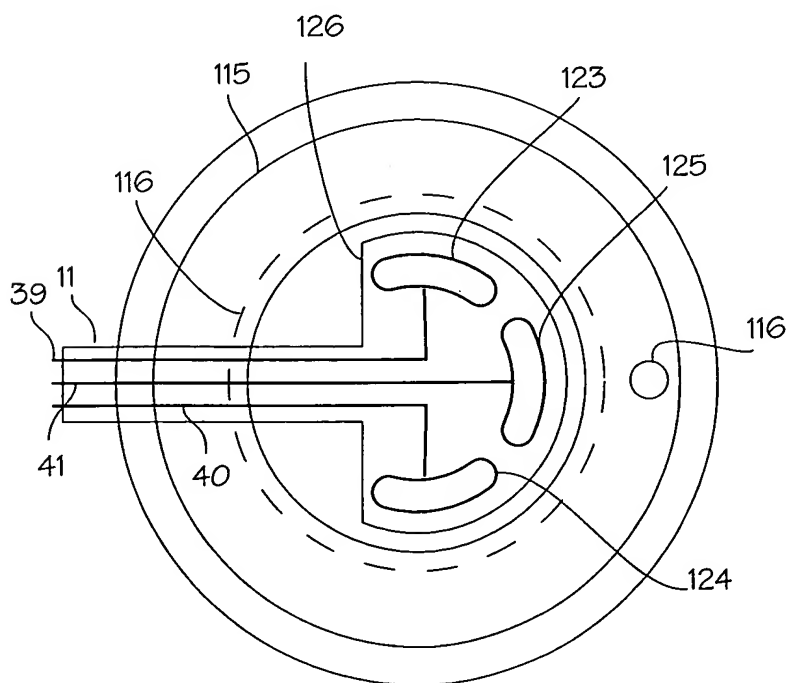


Fig. 10







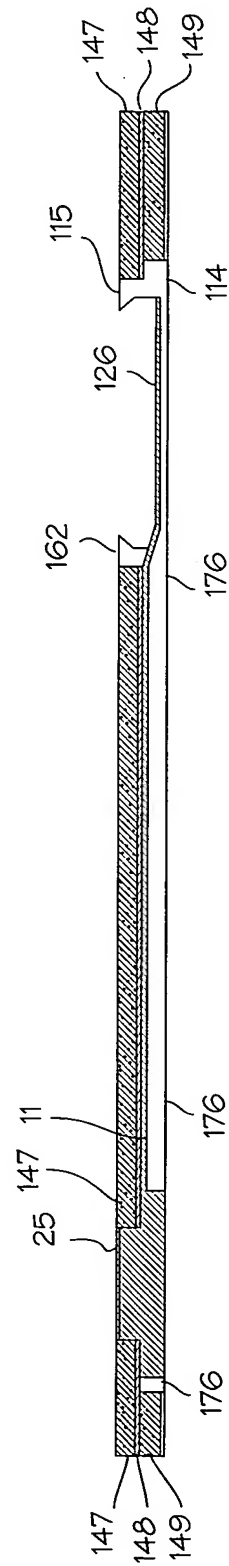


Fig. 15

Fig. 16

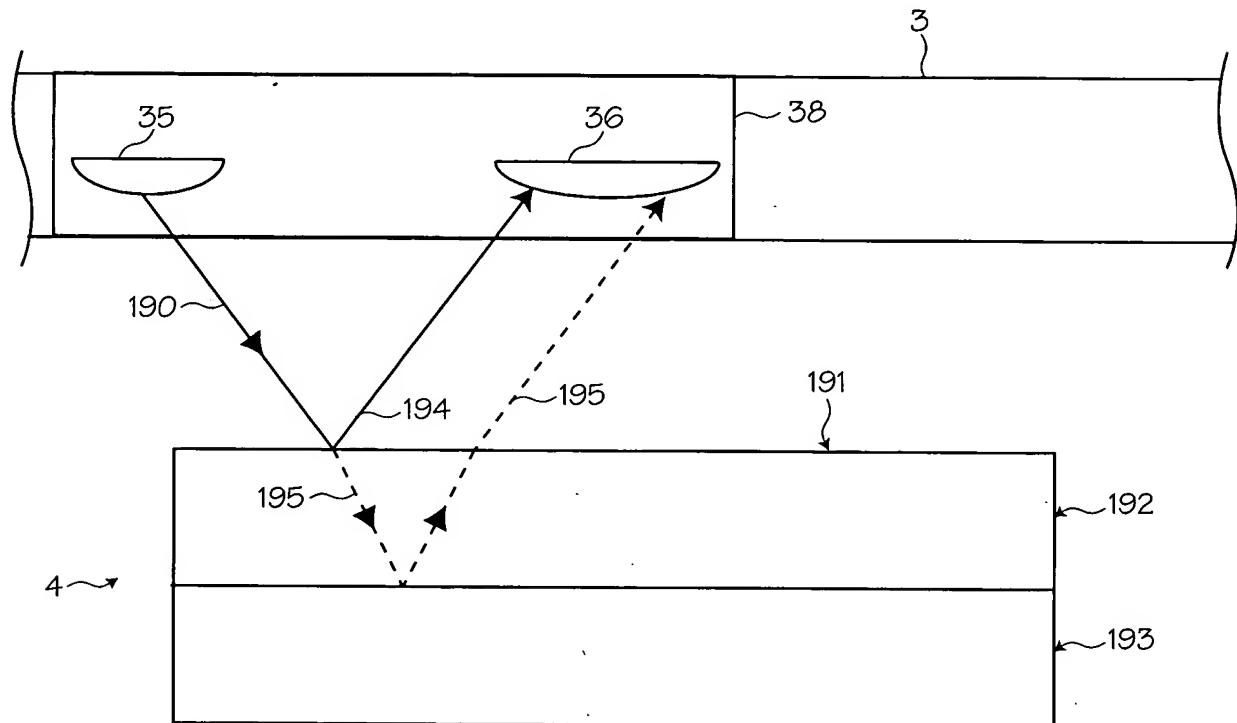


Fig. 17

